

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention	METHOD FOR UNIFORM REACTIVE ION ETCHING OF DUAL PRE-DOPED POLYSILICON REGIONS
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Application Number :

Confirmation Number:

First Named Applicant: Joyce Liu

Attorney Docket Number: FIS920030338US1

Art Unit:

Examiner:

Search string: (5912187 or 6322714 or 6352934 or 6399432 or 6458646 or 20030186492).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
4	1	5912187	1999-06-15	Blasko et al.		438	719
LT	2	6322714	2001-11-27	Nallan et al.	B1	216	67
LT	3	6352934	2002-03-05	Lee	B1	438	704
LT	4	6399432	2002-06-04	Zheng et al.	B1	438	232
LT	5	6458646	2002-10-01	Divakanuni et al.	B1	438	241

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
LT	1	20030186492	2003-10-02	Brown et al.	A1	438	200

Signature

Examiner Name	Date
<u>Tharman</u>	9/9/04